In the Claims:

Please cancel claims 1-44 without prejudice.

Please add new claims 45-135 as follows:

- 45. (New) An exposure apparatus for transferring an image onto a device, the exposure apparatus comprising:
 - a stage that retains the device, the stage including a device table;
 - a stage mover assembly for moving the stage; and
 - a chamber assembly that encircles the device and provides a device chamber around the device, the chamber assembly including a fixed section, a moving section that moves relative to the fixed section and substantially concurrently with the stage, a seal assembly that seals an intersection between the fixed section and the moving section during movement of the moving section, and a table seal that seals the moving section to the device table.
- 46. (New) The exposure apparatus of claim 45 wherein the table seal includes bellows that allow for motion to the device table relative to the moving section.
- 47. (New) The exposure apparatus of claim 45 wherein a portion of the stage mover assembly is positioned outside the device chamber.
- 48. (New) A device manufactured with the exposure apparatus according to claim 45.
- 49. (New) A wafer on which an image has been formed by the exposure apparatus of claim 45.

50. (New) An exposure apparatus for transferring an image onto a device, the exposure apparatus comprising:

a stage that retains the device; and

a chamber assembly that encircles the device and provides a device chamber around the device, the chamber assembly including (i) a fixed section that includes a top wall and four side walls, (ii) a moving section that moves relative to the fixed section, the moving section including a bottom wall, and (iii) a seal assembly that seals an intersection between the fixed section and the moving section during movement of the moving section.

- 51. (New) The exposure apparatus of claim 50 wherein the top wall, the side walls and the bottom wall cooperate to define a substantially rectangular shaped housing.
- 52. (New) The exposure apparatus of claim 51 wherein the seal assembly seals a bottom edge of the side walls to a top surface of the bottom wall.
- 53. (New) The exposure apparatus of claim 50 further comprising a stage mover assembly for moving the stage, wherein a portion of the stage mover assembly is positioned outside the device chamber.
- 54. (New) A device manufactured with the exposure apparatus according to claim 50.
- 55. (New) A wafer on which an image has been formed by the exposure apparatus of claim 50.
- 56. (New) An exposure apparatus for transferring an image onto a device, the exposure apparatus comprising:
 - a stage that retains the device; and

- a chamber assembly that encircles the device and provides a device chamber around the device, the chamber assembly including a fixed section, a moving section that moves relative to the fixed section, and a seal assembly that seals an intersection between the fixed section and the moving section during movement of the moving section, the seal assembly including a fluid bearing.
- 57. (New) The exposure apparatus of claim 56 further comprising a stage mover assembly for moving the stage, wherein a portion of the stage mover assembly is positioned outside the device chamber.
- 58. (New) A device manufactured with the exposure apparatus according to claim 56.



- 59. (New) A wafer on which an image has been formed by the exposure apparatus of claim 56.
- 60. (New) An exposure apparatus for transferring an image onto a device, the exposure apparatus comprising:
 - a stage that retains the device;
 - a stage mover assembly that moves the stage; and
 - a chamber assembly that encircles the device and provides a device chamber around the device, the chamber assembly including (i) a fixed section that includes a top wall and four side walls, (ii) a moving section that moves substantially concurrently with the stage, the moving section including a bottom wall, and (iii) a seal assembly that seals an intersection between the fixed section and the moving section during movement of the moving section.
- 61. (New) The exposure apparatus of claim 60 wherein the top wall, the side walls and the bottom wall cooperate to define a substantially rectangular shaped housing.

- 62. (New) The exposure apparatus of claim 60 wherein the seal assembly seals a bottom edge of the side walls to a top surface of the bottom wall.
- 63. (New) The exposure apparatus of claim 60 wherein a portion of the stage mover assembly is positioned outside the device chamber.
- 64. (New) A device manufactured with the exposure apparatus according to claim 60.
- 65. (New) A wafer on which an image has been formed by the exposure apparatus of claim 60.
- 66. (New) An exposure apparatus for transferring an image onto a device, the exposure apparatus comprising:
 - a stage that retains the device, the stage including a device table;
 - a stage mover assembly that moves the stage; and
 - a chamber assembly that encircles the device and provides a device chamber around the device, the chamber assembly including a moving section that moves substantially concurrently with the stage and a table seal that seals the moving section to the device table and allows for motion to the device table relative to the moving section.
- 67. (New) The exposure apparatus of claim 66 wherein the chamber assembly includes a fixed section and a seal assembly that seals an intersection between the fixed section and the moving section during movement of the moving section.
- 68. (New) The exposure apparatus of claim 66 wherein a portion of the stage mover assembly is positioned outside the device chamber.

- 69. (New) A device manufactured with the exposure apparatus according to claim 66.
- 70. (New) A wafer on which an image has been formed by the exposure apparatus of claim 66.
- 71. (New) A method for making a chamber assembly for an exposure apparatus that transfers an image onto a device, the exposure apparatus including a stage that retains the device and a stage mover assembly that moves the stage, the method comprising the steps of:

providing a fixed section;

providing a moving section that moves relative to the fixed section;

sealing an intersection between the fixed section and the moving section during movement of the moving section with a seal assembly; and

sealing a device table of the stage to the moving section with a table seal, the table seal allowing for motion to the device table relative to the moving section.

- 72. (New) The method of claim 71 including the step of positioning the moving section above the stage mover assembly.
- 73. (New) The method of claim 71 further comprising the step of moving the moving section substantially concurrently with the stage.
- 74. (New) The method of claim 71 further comprising the step of securing the moving section to the stage.
- 75. (New) A method for making an exposure apparatus including the steps of providing a stage and encircling the stage with a chamber assembly made in accordance with the method of claim 71.

- 76. (New) A method of making a wafer utilizing an exposure apparatus made by the method of claim 75.
- 77. (New) A method of making a device including at least the exposure process, wherein the exposure process utilizes the exposure apparatus made by the method of claim 75.
- 78. (New) A method for making a chamber assembly for an exposure apparatus that transfers an image onto a device, the exposure apparatus including a stage that retains the device and a stage mover assembly that moves the stage, the method comprising the steps of:

providing a fixed section that includes a top wall and four side walls;

providing a moving section that moves relative to the fixed section, the moving section including a bottom wall, and

sealing an intersection between the fixed section and the moving section during movement of the moving section with a seal assembly.

- 79. (New) The method of claim 78 wherein the step of sealing includes the step of sealing a bottom edge of the side walls to a top surface of the bottom wall.
- 80. (New) A method for making an exposure apparatus including the steps of providing a stage and encircling the stage with a chamber assembly made in accordance with the method of claim 78.
- 81. (New) A method of making a wafer utilizing an exposure apparatus made by the method of claim 80.
- 82. (New) A method of making a device including at least the exposure process, wherein the exposure process utilizes the exposure apparatus made by the method of claim 80.

83. (New) A method for making a chamber assembly for an exposure apparatus that transfers an image onto a device, the exposure apparatus including a stage that retains the device and a stage mover assembly that moves the stage, the method comprising the steps of:

providing a fixed section;

providing a moving section that moves relative to the fixed section;

securing the moving section to the stage; and

sealing a device table of the stage to the moving section with a table seal, the table seal allowing for motion to the device table relative to the moving section.

- 84. (New) The method of claim 83 further comprising the step of sealing an intersection between the fixed section and the moving section during movement of the moving section with a seal assembly.
- 85. (New) A method for making an exposure apparatus including the steps of providing a stage and encircling the stage with a chamber assembly made in accordance with the method of claim 83.
- 86. (New) A method of making a wafer utilizing an exposure apparatus made by the method of claim 85.
- 87. (New) A method of making a device including at least the exposure process, wherein the exposure process utilizes the exposure apparatus made by the method of claim 85.
- 88. (New) A method for making a chamber assembly for an exposure apparatus that transfers an image onto a device, the exposure apparatus including a stage that retains the device and a stage mover assembly that moves the stage, the method comprising the steps of:

providing a fixed section that includes a top wall and four side walls;

providing a moving section that moves relative to the fixed section, the moving section including a bottom wall; and

securing the moving section to the stage.

- 89. (New) The method of claim 88 further comprising the step of sealing a bottom edge of the side walls to a top surface of the bottom wall.
- 90. (New) The method of claim 88 further comprising the step of sealing an intersection between the fixed section and the moving section during movement of the moving section with a seal assembly.
- 91. (New) A method for making an exposure apparatus including the steps of providing a stage and encircling the stage with a chamber assembly made in accordance with the method of claim 88.
- 92. (New) A method of making a wafer utilizing an exposure apparatus made by the method of claim 91.
- 93. (New) A method of making a device including at least the exposure process, wherein the exposure process utilizes the exposure apparatus made by the method of claim 91.
- 94. (New) An exposure apparatus for transferring an image onto a device, the exposure apparatus comprising:
 - a stage that retains the device; and
 - a chamber assembly that encircles the device and provides a device chamber around the device, the chamber assembly including a fixed section and a moving section that moves relative to the fixed section, the moving section including at least one wall that defines at least a portion of the device chamber.

- 95. (New) The exposure apparatus of claim 94 wherein the fixed section includes at least one wall that defines at least a portion of the device chamber.
- 96. (New) The exposure apparatus of claim 95 wherein the fixed section includes a top wall and four side walls and the moving section includes a bottom wall.
- 97. (New) The exposure apparatus of claim 96 wherein the top wall, the side walls and the bottom wall cooperate to define a substantially rectangular shaped housing.
- 98. (New) The exposure apparatus of claim 96 further comprising a seal assembly that seals an intersection between the fixed section and the moving section during movement of the moving section.
- 99. (New) The exposure apparatus of claim 98 wherein the seal assembly seals a bottom edge of the side walls to a top surface of the bottom wall.
- 100. (New) The exposure apparatus of claim 98 wherein the seal assembly includes a fluid bearing.
- 101. (New) The exposure apparatus of claim 94 further comprising a stage mover assembly for moving the stage.
- 102. (New) The exposure apparatus of claim 101 wherein the moving section moves substantially concurrently with the stage.
- 103. (New) The exposure apparatus of claim 101 wherein the moving section is secured to the stage.
- 104. (New) The exposure apparatus of claim 101 wherein a portion of the stage mover assembly is positioned outside the device chamber.

- 105. (New) The exposure apparatus of claim 101 wherein the stage mover assembly is entirely positioned outside the device chamber.
- 106. (New) The exposure apparatus of claim 94 wherein the stage includes a device table and the chamber assembly includes a table seal that seals the moving section to the device table.
- 107. (New) The exposure apparatus of claim 106 wherein the table seal allows for motion to the device table relative to the moving section.
- 108. (New) A device manufactured with the exposure apparatus according to claim 94.
- 109. (New) A wafer on which an image has been formed by the exposure apparatus of claim 94.
- 110. (New) An exposure apparatus for transferring an image onto a device, the exposure apparatus comprising:
 - a stage that retains the device, the stage including a device table; and
 - a chamber assembly that encircles the device and provides a device chamber around the device, the chamber assembly including a moving section and a table seal that seals the moving section to the device table.
- 111. (New) The exposure apparatus of claim 110 wherein the table seal allows for motion to the device table relative to the moving section.
- 112. (New) The exposure apparatus of claim 110 further comprising a stage mover assembly for moving the stage.

- 113. (New) The exposure apparatus of claim 112 wherein the moving section moves substantially concurrently with the stage.
- 114. (New) The exposure apparatus of claim 112 wherein the moving section is secured to the stage.
- 115. (New) The exposure apparatus of claim 112 wherein a portion of the stage mover assembly is positioned outside the device chamber.
- 116. (New) The exposure apparatus of claim 112 wherein the stage mover assembly is entirely positioned outside the device chamber.
- 117. (New) The exposure apparatus of claim 110 wherein the chamber assembly further includes a fixed section and a seal assembly, wherein the moving section moves relative to the fixed section, the seal assembly sealing an intersection between the fixed section and the moving section during movement of the moving section.
- 118. (New) The exposure apparatus of claim 117 wherein the fixed section includes a fixed wall and the moving section includes a moving wall.
- 119. (New) The exposure apparatus of claim 118 wherein the fixed section and the moving section cooperate to define a substantially rectangular shaped housing.
- 120. (New) The exposure apparatus of claim 118 wherein the seal assembly seals the fixed wall to the moving wall.
- 121. (New) The exposure apparatus of claim 117 wherein the seal assembly includes a fluid bearing.

- 122. (New) A device manufactured with the exposure apparatus according to claim 110.
- 123. (New) A wafer on which an image has been formed by the exposure apparatus of claim 110.
- 124. (New) A method for making a chamber assembly for an exposure apparatus that transfers an image onto a device, the exposure apparatus including a stage that retains the device and a stage mover assembly that moves the stage, the method comprising the steps of:

providing a fixed section; and

providing a moving section that moves relative to the fixed section, the moving section including at least one wall that defines at least a portion of a device chamber around the device.

- 125. (New) The method of claim 124 wherein the fixed section includes at least one wall that defines at least a portion of the device chamber around the device.
- 126. (New) The method of claim 125 wherein the step of providing the fixed section includes providing a top wall and four side walls and the step of providing the moving section includes providing a bottom wall.
- 127. (New) The method of claim 126 further comprising the step of sealing the side walls to the bottom wall with a seal assembly.
- 128. (New) The method of claim 124 further comprising the step of sealing an intersection between the fixed section and the moving section during movement of the moving section with a seal assembly.

- 129. (New) The method of claim 124 further comprising the step of moving the moving section substantially concurrently with the stage.
- 130. (New) The method of claim 124 further comprising the step of securing the moving section to the stage.
- 131. (New) The method of claim 124 further comprising the step of sealing a device table of the stage to the moving section with a table seal, the table seal allowing for motion to the device table relative to the moving section.
- 132. (New) The method of claim 131 including the step of positioning the moving section above the stage mover assembly.
- 133. (New) A method for making an exposure apparatus including the steps of providing a stage and encircling the stage with a chamber assembly made in accordance with the method of claim 124.
- 134. (New) A method of making a wafer utilizing an exposure apparatus made by the method of claim 133.
- 135. (New) A method of making a device including at least the exposure process, wherein the exposure process utilizes the exposure apparatus made by the method of claim 133.